

MAY 17 2006

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant:	Hong-Jyh Li	Examiner:	Phillip A. Johnston
Serial No.:	10/816,503	Group Art Unit:	2881
Filed:	April 1, 2004	Docket No.:	2004P51130US/I331.128.101
Title:	PLASMA ION IMPLEMENTATION SYSTEM		

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**AMENDMENT/REPLY**

**Mail Stop RCE**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

This Amendment/Reply accompanies the Request for Continued Examination (RCE) 37 CFR 1.114 and is in reply to the Final Office Action mailed March 17, 2006. Please amend the above-identified patent application as follows: